|  |  |  |  |  |  |  |  |  |  |  |  |  |  |
| --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- | --- |
| **Technical Support Application**  Receipt No.: | | | | Approval |  | | |  | | |  | |  |
|  | | |  | | |  | |  |
| Address | Post Code: | | | Business Registration No. | | | |  | | | | | |
|  | | | Applicant | | | |  | | | | | |
| Business Type | | |  | | Business Category | | |  | |
| Company |  | | | Contact | | | | Tel | |  | | | |
| Fax | |  | | | |
| Representative |  | | | E-mail | |  | | | |
| Requested Process | | Qty. | Request | | | Size (inch) | | | | Polishing Status | | | |
| Silicon X-Ray Sensor Production | | 7 | Sensor production | | | 6 | | | | Cross Section | | | |
| Material | | Thickness | Impurities (Resistive) | | | P. Flat zone Size (mm) | | | | Processing Direction | | | |
| Silicon | | 675µm | N-/N+ type | | | 57.5 | | | | 111 | | | |
| Wafer History.  (Current Wafer Status) | |  | | | | | | | | Others | | | |
|  | | | |
| I hereby apply for silicon process support from your research institute as stated above.  (Date) (Month), (Year)  Organization: Applicant: (Signature) | | | | | | | | | | | | | |

\* ~If the content of the item is deemed inappropriate, it can be changed.

|  |  |  |  |  |
| --- | --- | --- | --- | --- |
| **Receipt** | | | | |
| Company: Receipt No. : | | | | |
| Model | Qty. | Description | Expected Completion Date | Received by |
|  |  |  |  |  |

**\* ETRI is designated as a taxable entity from January 1st, 2015. Accordingly, a value-added tax (10%) will be imposed.**

**\* Bank Account for Deposit: 27033440818741 (Woori Bank, Account Holder: Electronics and Telecommunications Research Institute).**